

# ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention	SAMPLE MOUNT FOR PERFORMING SPUTTER-DEPOSITION IN A FOCUSED ION BEAM (FIB) TOOL
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Application Number :

Confirmation Number:

First Named Applicant: Lawrence Fischer

Attorney Docket Number: FIS920030137

Art Unit:

Examiner:

Search string: ( 5434422 or 5635836 or 5922179 or 6407850 or 20020005492 or 20020050565 ).pn

## US Patent Documents

**Note: Applicant is not required to submit a paper copy of cited US Patent Documents**

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5434422	1995-07-18	Iwamoto et al.			
	2	5635836	1997-06-03	Kirtley et al.			
	3	5922179	1999-07-13	Mitro et al.			
	4	6407850	2002-06-18	Rojo et al.			

## US Published Applications

**Note: Applicant is not required to submit a paper copy of cited US Published Applications**

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20020005492	2002-01-17	Hashikawa et al.			
	2	20020050565	2002-05-02	Tokuda et al.			

## Signature

Examiner Name	Date